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PATENT APPLICATION
28/2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kenji NISHI

Application No.: 10/026,909

Filed: December 27, 2001

Docket No.: 111586

For: MANUFACTURING METHOD IN MANUFACTURING LINE, MANUFACTURING
METHOD FOR EXPOSURE APPARATUS, AND EXPOSURE APPARATUS

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CLAIM FOR PRIORITY

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

The benefit of the filing date of the following prior foreign application filed in the following foreign country is hereby requested for the above-identified patent application and the priority provided in 35 U.S.C. §119 is hereby claimed:

Japanese Patent Application No. 2001-395489 filed December 26, 2001.

In support of this claim, a certified copy of said original foreign application:

_____ is filed herewith.

_____ was filed on _____ in Parent Application No. _____ filed _____.

X will be filed at a later date.

It is requested that the file of this application be marked to indicate that the requirements of 35 U.S.C. §119 have been fulfilled and that the Patent and Trademark Office kindly acknowledge receipt of this document.

Respectfully submitted,

Thomas J. Pardini
James A. Oliff
Registration No. 27,075

Thomas J. Pardini
Registration No. 30,411

JAO:TJP/kaf

Date: January 9, 2002

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

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